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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Mineo HIRAMATSU, et al.



Serial No.: 10/569,838

Group Art Unit: Unknown

Filed: February 24, 2006

Examiner: Unknown

For: METHOD FOR PRODUCING CARBON NANOWALLS,  
CARBON NANOWALL, AND APPARATUS FOR PRODUCING  
CARBON NANOWALLS

Honorable Commissioner of Patents  
Alexandria, Virginia 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Sir:

Under the provisions of 37 CFR §1.97 through §1.98 and pursuant to Applicant duty of disclosure under 37 CFR §1.56, Applicant respectfully brings the following documents cited in the Japanese Office Action in a counterpart foreign application and listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which Applicant is aware.

In compliance with the concise explanation requirement under 37 CFR §1.98(a)(3) for foreign language documents, Applicant encloses herewith a copy of the Japanese Office Action citing such documents, together with an English-language version (if not already included) of that portion of the Office Actions indicating the degree of relevance found by the foreign office. Further, English-language abstracts are attached to the references.

The enclosed documents are (1) Office Action of Japanese patent application No. 2005-513488 issued on September 26, 2006, (2) its partial translation, (3) its cited reference Nos. 11-067490, 2003-173980, and 2001-81570 (4) and an article by Takashi Hirao, et al.

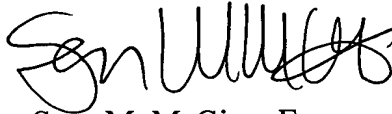
Serial No.: 10/569,838  
Docket No. F06-436-US  
FUJIT.081

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Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit  
Account No. 50-0481.

Date: 12/27/06  
**MCGINN INTELLECTUAL PROPERTY**  
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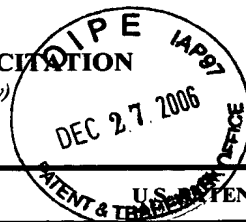
Respectfully submitted,



Sean M. McGinn, Esq.  
Registration No. 34,386

# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



Docket Number (Optional) <b>F06-436-US</b>	Application Number <b>10/569,838</b>
Applicant(s) <b>Mineo HIRAMATSU, et al.</b>	
Filing Date <b>February 24, 2006</b>	Group Art Unit <b>Unknown</b>

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		2001-081570	03/27/2001	JAPAN			ABS	
		11-067490	03/09/1999	JAPAN			ABS	
		2003-173980	06/20/2003	JAPAN			ABS	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Office Action of Japanese Patent Application No. 2005-513488, with partial English translation
		"Formation of Vertically Aligned Carbon Nanotubes by Dual-RF-Plasma Chemical Vapor Disposition", by Takashi HIRAO, et al.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.